Electronic Supplementary Material (ESI) for Journal of Materials Chemistry C.

Supporting Information

Pore-free Bubbling Delamination of Chemical Vapor Deposited Graphene from Copper Foils

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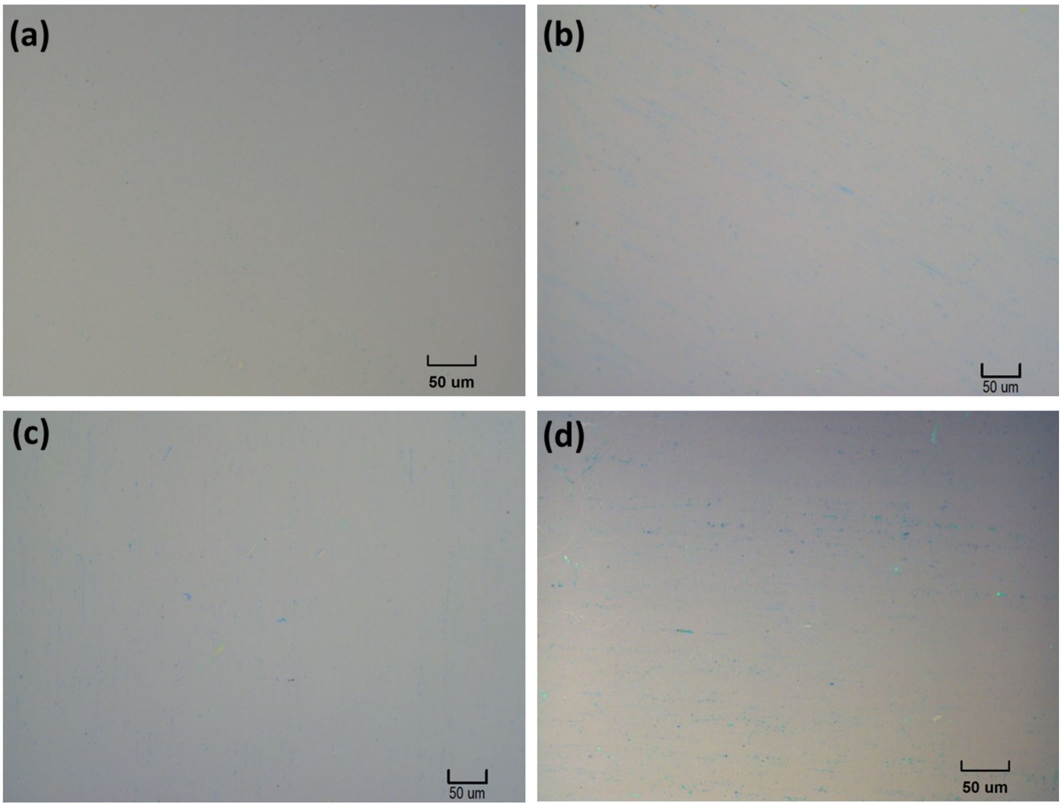

Figure S1. The morphology of etch transferred graphene with PMMA supporting layer thickness of (a) 600 nm; (b) 420 nm; (c) 340nm; and (d) 290 nm respectively.